What is claimed is:

1. An organic EL device comprising:

a lower electrode formed on a substrate;

an organic EL layer formed on the lower electrode;

an upper electrode formed on the organic EL layer;

a sealing member for sealing said lower electrode, organic EL layer and upper electrode on said substrate so that they are covered with the sealing member, wherein said sealing member is made of an aluminum material coated with an insulating layer in its inner surface.

2. An organic EL device according to claim 1, wherein said aluminum material is a flexible aluminum sheet.

3. An organic EL device according to claim 1, wherein said insulating layer is an aluminum oxide layer formed by anodic oxidation of said aluminum material.

4. An organic EL device according to claim 1, wherein said insulating layer is a porous aluminum oxide layer.

5. An organic EL device according to claim 3, wherein said aluminum sheet is formed in such a manner that a surface of said aluminum oxide layer is subjected to gas flow-out treatment in

vacuum, and thereafter said lower electrode, organic EL layer and upper electrode are sealed on the substrate in an atmosphere of inert gas.

6. A method of manufacturing an organic EL device comprising the steps of:

forming a lower electrode formed on a substrate;

forming an organic EL layer on the lower electrode;

forming an upper electrode on the organic EL layer to provide the organic EL device;

preparing an aluminum material coated with an insulating layer in at least its inner surface; and

sealing said organic EL device so that it is covered with said aluminum material.

7. A method of manufacturing an organic EL device according to claim 6, wherein

said step of preparing the aluminum material comprises the steps of:

making anodic oxidation to form an aluminum oxide layer on a surface of a flexible aluminum sheet; and

removing gas contained within said aluminum oxide layer, and

said step of sealing said organic EL device comprises the step of:

fixing said aluminum sheet with the gas removed on a surface of said substrate in an atmosphere of inert gas or in vacuum.

8. A method of manufacturing an organic EL device according to claim 1, wherein said step of removing gas is to heat the aluminum sheet with the aluminum oxide layer for several-60 minutes at 60-300 °C in vacuum.

9. A method of manufacturing an organic EL device according to claim 7, wherein said step of making anodic oxidation is to form a porous aluminum oxide layer; and

said step of removing gas is to heat said aluminum sheet in vacuum so that impurities contained in pores of said porous aluminum oxide layer are discharged.

10. A method of manufacturing an organic EL device according to claim 7, wherein

said step of sealing said organic EL device comprises the steps of:

mounting said organic EL device and aluminum sheet in a sealing chamber and once heating them at room temperature- 150 °C in vacuum;

introducing inert gas into the sealing chamber; and

fixing said aluminum sheet to said substrate through an

adhesive and heating it.

11. A method of manufacturing an organic EL device according to claim 7, wherein said inert gas is argon gas.

add c2